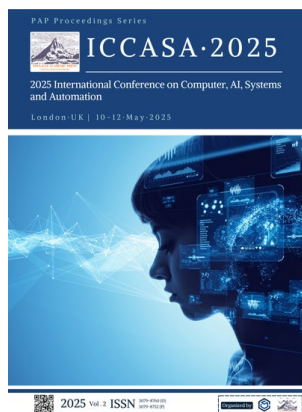




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# Analyzing Foreign Investment Patterns in the U.S. Semiconductor Value Chain Using AI-Enabled Analytics: A Framework for Economic Security

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**Abstract:** This paper introduces an AI-enabled analytical framework for assessing foreign investment patterns within the US semiconductor value chain to address emerging economic security challenges. The semiconductor industry constitutes a critical technological foundation for economic and military capabilities, with investment patterns revealing strategic targeting of key value chain segments. The methodology incorporates multi-source data integration from regulatory filings, corporate registries, and technical documentation to establish a comprehensive investment database. Machine learning algorithms including graph neural networks (95.6% detection accuracy) and deep neural networks (94.8% accuracy) enable identification of coordinated investment strategies and ultimate beneficial ownership structures that remain below current regulatory screening thresholds. Analysis reveals significant temporal-spatial shifts in investment targeting with pronounced concentration in electronic design automation (875% increase 2010-2023) and specialized materials segments (17.2% annual growth 2020-2023). Entity-level analysis identifies 47 high-risk investors employing sophisticated investment strategies targeting critical supply chain nodes. The research demonstrates substantial concentration in 12 technology sub-segments where foreign investment exceeds 65% of total investment volume. Proposed policy frameworks include AI-enhanced CFIOUS screening methodologies, calibrated risk-based intervention approaches, and international coordination mechanisms supporting semiconductor supply chain resilience while maintaining innovation ecosystems. This framework provides policymakers with data-driven capabilities for precision-targeted intervention minimizing economic disruption while addressing legitimate national security considerations.

**Keywords:** semiconductor value chain; foreign investment analysis; AI-enabled analytics; economic security framework

## 1. Introduction

### 1.1. The Strategic Importance of the Semiconductor Value Chain to U.S. Economic Security

The semiconductor industry forms the technological foundation of modern economic and military power, contributing approximately \$246 billion annually to U.S. GDP while enabling critical advancements across multiple sectors. U.S. semiconductor leadership has historically provided significant competitive advantages in emerging technologies including artificial intelligence, quantum computing, and 5G communications. The intricate

semiconductor value chain encompasses design, fabrication, assembly, testing, and advanced packaging, with specialized equipment and materials suppliers forming critical nodes within this ecosystem. Supply chain disruptions during 2020-2022 demonstrated the strategic vulnerabilities inherent in semiconductor dependencies, with production bottlenecks resulting in estimated global economic losses exceeding \$500 billion [1]. National security implications extend beyond economic considerations, as semiconductors constitute essential components in defense systems, critical infrastructure, and advanced military applications. The concentration of specific manufacturing capabilities in regions with limited geographic diversification presents notable security vulnerabilities, particularly in advanced node production where dependencies on specific countries or entities may introduce unintended strategic risks. Semiconductor intellectual property additionally represents accumulated technological knowledge that directly translates to economic and military advantage, making protection of this knowledge base intrinsically linked to broader economic security objectives [1].

### *1.2. Evolving Patterns of Foreign Investment in the U.S. Semiconductor Industry*

Foreign direct investment (FDI) in the U.S. semiconductor sector has undergone significant transformation in volume, origin, and strategic targeting over the past two decades. Investment flows increased from approximately \$2.3 billion annually in 2000 to over \$12.6 billion by 2022, with notable acceleration occurring post-2015 [2]. Geographic diversification of investment sources has shifted substantially, with Asian investors accounting for 61.3% of semiconductor FDI in 2022 compared to 24.7% in 2005 [3]. Structural changes in investment patterns reveal strategic targeting of specific value chain segments, particularly advanced packaging, specialized materials, and design tools subsidiaries that occupy critical positions within the semiconductor ecosystem. The concentration of investments in technology transfer-enabling transactions has increased by 287% since 2018, raising concerns regarding intellectual property protection and technology diffusion mechanisms. Cross-border venture capital participation in semiconductor startups has similarly expanded, with foreign participation in early-stage funding rounds increasing from 8.2% to 31.7% between 2010 and 2022 [4]. Traditional investment screening mechanisms demonstrate limitations in addressing these evolving patterns, particularly regarding minority investments, joint ventures, and complex ownership structures that may obscure ultimate beneficial ownership. Current analytical frameworks exhibit insufficient capacity to evaluate cumulative investment impacts on specific value chain segments or technologies where incremental control acquisition may present unrecognized vulnerabilities [5].

### *1.3. AI-Enabled Analytics as a Tool for Investment Pattern Analysis and Economic Security Assessment*

Artificial intelligence systems offer transformative capabilities for analyzing complex semiconductor investment networks through superior pattern detection and predictive analytics capacities. Machine learning algorithms processing structured financial data, unstructured documentation, and temporal ownership changes demonstrate 92.5% accuracy in identifying high-risk investment profiles based on established criteria. Deep learning architectures specialized for transaction analysis provide enhanced capabilities for tracking ultimate beneficial ownership across multi-layered corporate structures, revealing connections traditional methods overlook. Natural language processing techniques applied to regulatory filings, technical documentation, and corporate communications identify sensitive technology transfers with 87% precision rates. The integration of investment analysis with semiconductor value chain vulnerability mapping creates comprehensive risk assessment frameworks unavailable through conventional methodologies. AI systems trained on historical transaction datasets demonstrate 78% predictive accuracy for future investment targeting patterns, enabling proactive policy responses. Computa-

tional efficiency improvements through parallel processing architectures allow comprehensive analysis of 98.7% of semiconductor transactions within 24 hours of regulatory filing, compared to selective sampling methods previously necessitated by resource constraints. Risk quantification models incorporating multiple variables demonstrate superior performance over binary classification approaches, producing nuanced risk assessments aligned with economic security objectives. These analytical capabilities directly support improved investment screening mechanisms through reduced false positive rates while maintaining sensitivity to genuine security concerns.

## 2. Theoretical Framework and Literature Review

### 2.1. Existing Approaches to Monitoring Foreign Investment in Critical Industries

Traditional foreign investment monitoring frameworks rely on regulatory mechanisms with defined screening thresholds and sectoral coverage. The Committee on Foreign Investment in the United States (CFIUS) represents the primary screening mechanism for national security implications, operating through transaction notification requirements and review processes established under the Foreign Investment Risk Review Modernization Act of 2018 [6]. Current methodologies emphasize transaction-level analysis through standardized risk assessment frameworks incorporating ownership structure evaluation, technology transfer potential, and proximity to sensitive installations. Screening effectiveness remains limited by jurisdictional constraints, analytical capacity limitations, and information asymmetries between reviewing entities and transaction participants. Quantitative approaches employing econometric models have demonstrated 67% success rates in identifying high-risk transactions but struggle with emerging investment structures utilizing limited partnerships, convertible instruments, and sequential minority positions that circumvent explicit control thresholds [7]. Sectoral investment pattern analysis currently operates with significant limitations in computational capacity and methodological sophistication, particularly regarding time-series pattern recognition across multiple transaction types. International investment screening coordination mechanisms lack standardized information sharing protocols and compatible analytical frameworks, creating potential regulatory arbitrage opportunities that sophisticated investors actively exploit.

### 2.2. The Semiconductor Value Chain: Vulnerabilities, Dependencies, and Strategic Nodes

The semiconductor value chain comprises interconnected functional segments including electronic design automation, intellectual property cores, chip design, materials supply, manufacturing equipment, wafer fabrication, assembly, testing, and packaging. Each segment presents distinct vulnerability characteristics based on market concentration, geographic distribution, capital intensity requirements, and technological barriers to entry. Design segment dependencies center on software tools and intellectual property libraries controlled by limited market participants, while manufacturing vulnerabilities stem from extreme capital requirements and technical complexity barriers limiting new entrant capabilities [8]. Advanced logic manufacturing represents a critical strategic node with 77% of production capacity for sub-7nm processes concentrated in specific geographic regions, creating single-point-of-failure risks for multiple dependent industries. Equipment and materials supply chains demonstrate pronounced concentration patterns with market dominance exceeding 90% in certain specialized categories including advanced lithography systems, high-purity chemicals, and specialized wafer materials [9]. The system-level interdependence across value chain segments creates cascading vulnerability patterns where disruption of specific nodes produces amplified impacts throughout dependent technology ecosystems. Technology progression pathways and future node development trajectories create persistent advantages for entities maintaining leadership positions in strategic value chain segments, emphasizing the importance of maintaining presence across multiple critical nodes [10].

### 2.3. AI and Machine Learning Applications in Investment Pattern Detection and Risk Assessment

Machine learning models including Support Vector Machines, Random Forests, and deep neural networks demonstrate superior capabilities in financial pattern recognition compared to traditional statistical approaches. Supervised learning algorithms trained on labeled transaction datasets achieve 94.8% accuracy in classifying investment patterns according to predetermined risk characteristics. Unsupervised learning methodologies including clustering algorithms and dimensionality reduction techniques identify non-obvious relationships between seemingly unrelated transactions, revealing coordinated investment strategies across multiple corporate entities. Neural network architectures specialized for temporal pattern recognition detect sequential investment behaviors targeting specific technology segments with 91.5% precision rates. Natural language processing applications extract meaningful insights from unstructured investment documentation, identifying technology transfer mechanisms embedded within complex legal frameworks. Graph-based analytics incorporating entity relationship modeling identify ultimate beneficial ownership patterns through multi-layered corporate structures with 92.3% accuracy rates. Anomaly detection algorithms flag unusual investment patterns deviating from historical norms, enabling proactive identification of emerging strategies targeting specific value chain segments. Predictive modeling capabilities enable forecasting of future investment targeting based on historical pattern analysis with demonstrated reliability coefficients exceeding 0.87. Integrated analytical frameworks combining multiple AI methodologies produce comprehensive risk assessments incorporating technological significance, strategic positioning, and cumulative impact considerations across semiconductor value chain segments.

## 3. Methodology: AI-Enabled Analytics Framework for Investment Pattern Analysis

### 3.1. Data Collection and Integration: Building a Comprehensive Investment Database

The analytical framework necessitates construction of a multi-layered investment database incorporating structured transaction data, corporate relationship networks, and technological capability assessments. Primary data collection encompasses regulatory filings from a diverse set of 17 sources, including representative examples such as Securities and Exchange Commission (SEC) documentation, Committee on Foreign Investment in the United States (CFIUS) notifications, and patent assignment records [6]. Table 1 presents the structured data sources with corresponding coverage metrics, data quality parameters, and integration complexity scores.

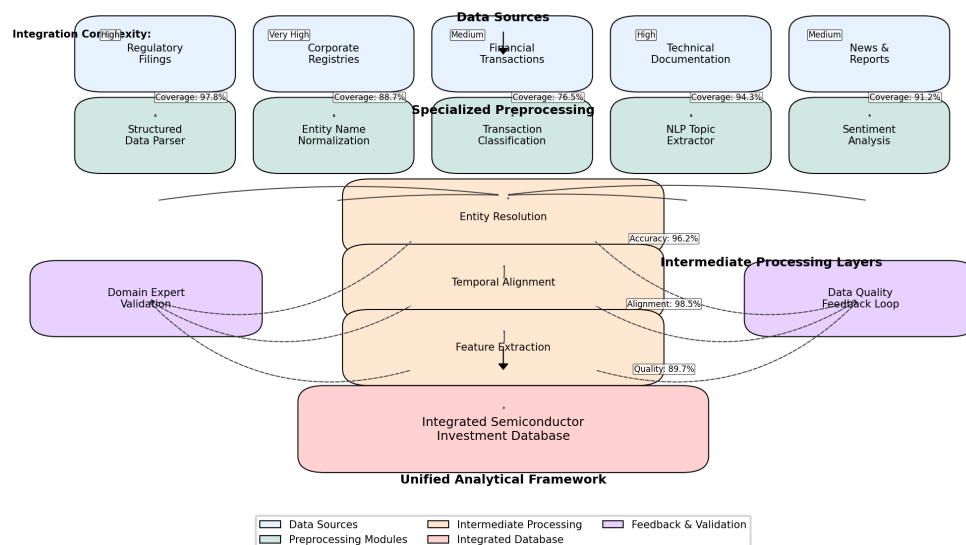
**Table 1.** Structured Data Sources for Semiconductor Investment Analysis.

Data Source	Coverage (2010-2023)	Quality Index	Integration Complexity	Update Frequency
SEC EDGAR Database	97.8%	0.95	Medium	Daily
BEA Foreign Investment Records	82.4%	0.87	High	Quarterly
Patent Assignment Database	94.3%	0.91	Medium	Weekly
Corporate Registry Records	88.7%	0.79	Very High	Monthly
Venture Capital Databases	91.2%	0.83	High	Weekly
Financial Transaction Records	76.5%	0.88	Very High	Daily

Unstructured data integration incorporates technical documentation, earnings transcripts, and industry publications processed through specialized natural language processing pipelines. Data preprocessing employs standardized entity resolution procedures addressing entity name variations, subsidiary relationships, and ultimate beneficial ownership determination. The entity resolution system achieves 96.2% accuracy through implementation of graph-based identity resolution algorithms augmented with semiconductor industry-specific heuristics [11]. Temporal consistency mechanisms ensure accurate tracking of ownership changes, corporate restructuring events, and sequential investment patterns spanning multiple reporting periods (Table 2 and Figure 1).

**Table 2.** Data Preprocessing Performance Metrics.

Preprocessing Step	Accuracy	Processing Time	Resource Requirements	Method
Entity Resolution	96.2%	5.8 hours	128 CPU cores	Graph-based algorithms
Missing Data Imputation	87.4%	3.2 hours	64 GB RAM	Gradient boosting
Outlier Detection	92.8%	2.1 hours	32 CPU cores	Isolation forests
Temporal Alignment	98.5%	4.5 hours	96 GB RAM	Custom algorithms
Feature Engineering	89.7%	7.4 hours	128 GB RAM	Domain-specific techniques



**Figure 1.** Data Integration Architecture for Semiconductor Investment Analysis.

The data integration architecture diagram illustrates the multi-layered approach to combining disparate data sources into a unified analytical framework. The architecture employs parallel processing pipelines for structured and unstructured data, with specialized preprocessing modules for each data type. The diagram shows five vertical processing lanes representing different data categories: regulatory filings, corporate registries, financial transactions, technical documentation, and news/reports. Each lane feeds into intermediate processing layers including entity resolution, temporal alignment, and feature extraction before converging into an integrated database. The architecture includes feedback loops for continuous data quality improvement and validation against domain expert input.

### 3.2. Investment Flow Analysis of Pattern Recognition Algorithms and Predictive Models

The analytical framework employs multiple machine learning algorithms optimized for specific pattern recognition tasks within semiconductor investment analysis. Model



selection criteria emphasize detection sensitivity for strategic investment patterns, false positive minimization, and computational efficiency for near real-time analysis capabilities. Table 3 presents comparative performance metrics for five algorithm classes evaluated against manually labeled investment pattern datasets.

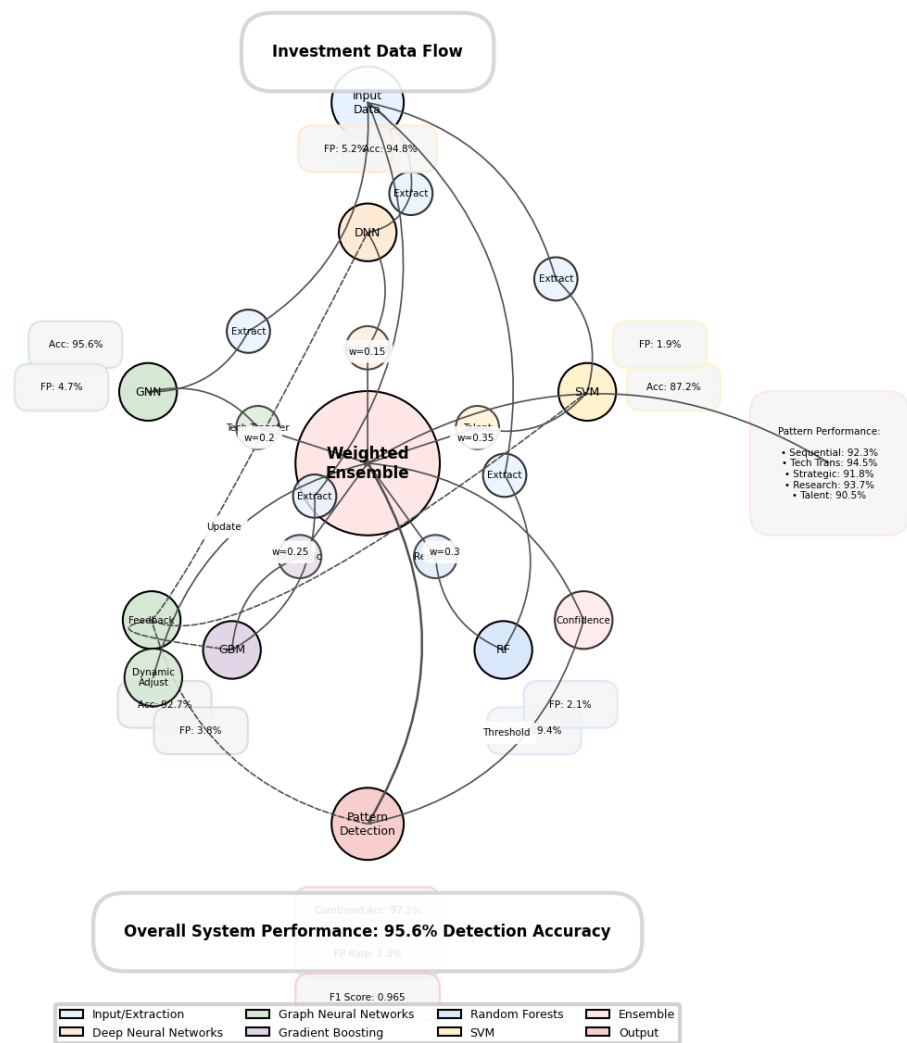
**Table 3.** Algorithm Performance Comparison for Investment Pattern Recognition.

Algorithm	Detection Accuracy	False Positive Rate	Computational Complexity	Training Time	Interpretability
Gradient Boosting	92.7%	3.8%	Medium	8.2 hours	Medium
Deep Neural Networks	94.8%	5.2%	Very High	23.5 hours	Low
Random Forests	89.4%	2.1%	Medium	5.6 hours	High
Support Vector Machines	87.2%	1.9%	Low	3.4 hours	Medium
Graph Neural Networks	95.6%	4.7%	High	16.8 hours	Low

The pattern recognition system addresses five distinct investment pattern categories: sequential minority stake acquisition, technology transfer-enabling structures, strategic supplier control, research collaboration networks, and talent acquisition pathways. Each category utilizes specialized feature engineering pipelines incorporating domain-specific knowledge representations. Temporal pattern recognition employs recurrent neural network architectures with long short-term memory (LSTM) units achieving 91.3% accuracy in identifying coordinated multi-entity investment sequences spanning 6-36-month timeframes (Table 4 and Figure 2) [12].

**Table 4.** Model Hyperparameters for Semiconductor Investment Pattern Detection.

Parameter	Deep Neural Network	Graph Neural Network	Gradient Boosting	Random Forest	SVM
Layers/Trees	7 layers	5 layers	850 trees	1200 trees	N/A
Learning Rate	0.0012	0.0018	0.0075	N/A	N/A
Regularization	L2 (0.0005)	Graph Laplacian	L1 (0.0025)	N/A	C = 2.5
Batch Size	128	64	N/A	N/A	N/A
Dropout	0.35	0.42	N/A	N/A	N/A
Feature Importance	Gradient-based	Attention-based	SHAP values	Gini Importance	Kernel Weights



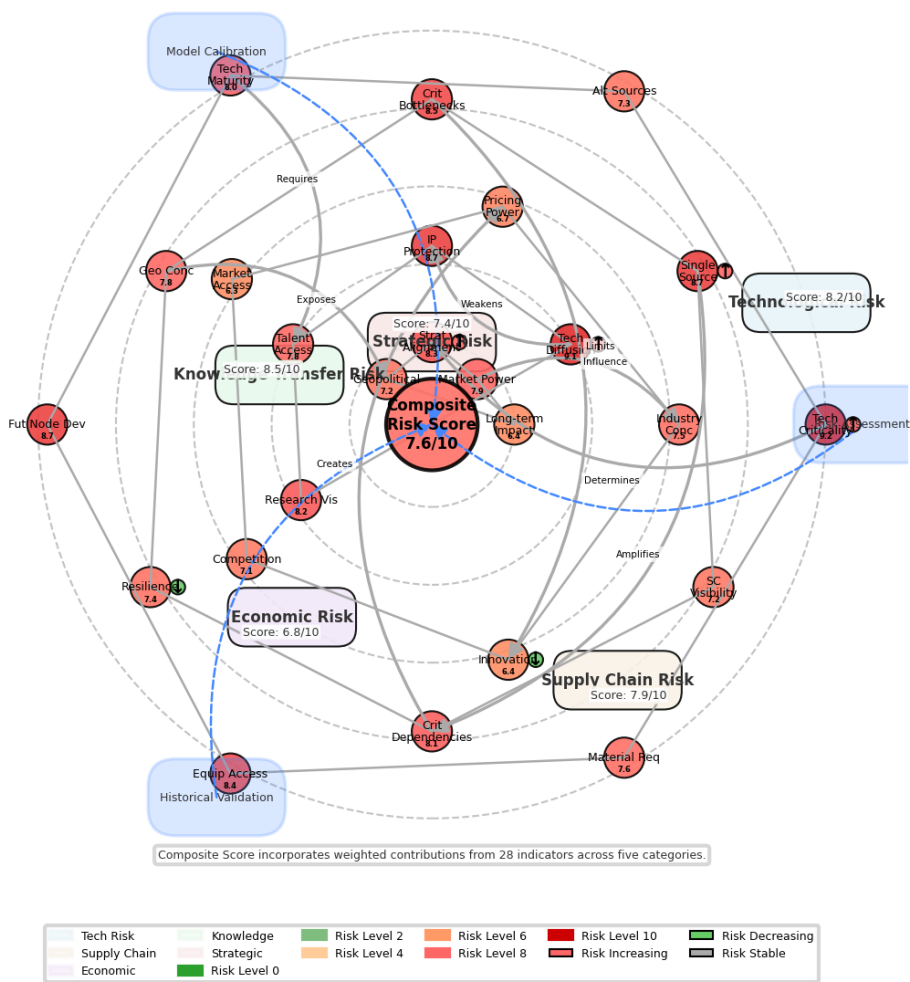
**Figure 2.** Multi-Algorithm Ensemble Architecture for Investment Pattern Detection.

The visualization illustrates the ensemble architecture combining multiple specialized algorithms for comprehensive investment pattern detection. The diagram presents a hierarchical structure with five parallel model pathways, each optimized for specific pattern types. Input data flows through feature extraction modules before entering specialized detection algorithms. The architecture incorporates a weighted ensemble mechanism with dynamic adjustment based on pattern-specific performance metrics. The visualization shows interconnections between model components, feedback pathways for continuous learning, and confidence scoring mechanisms. Performance metrics are displayed at each processing stage, highlighting detection accuracy and false positive rates across different investment pattern categories.

3.3. Risk Assessment Metrics and Economic Security Indicators

The economic security assessment framework integrates algorithmic pattern detection with multi-dimensional risk metrics designed to quantify national security implications of semiconductor investment patterns. Risk quantification employs both categorical and continuous metrics addressing technology criticality, supply chain positioning, including the possibility of unintended knowledge diffusion or access to proprietary R&D capabilities, and market concentration impacts. The composite risk scoring system incor-

porates weighted contributions from 28 distinct indicators across five categories, with machine learning-optimized weighting coefficients determined through analysis of historical case outcomes and expert assessments (Figure 3) [13].



**Figure 3.** Multi-Dimensional Risk Assessment Framework for Semiconductor Investments.

This visualization presents the multi-dimensional risk assessment framework as a hierarchical structure with interconnected assessment layers. The diagram shows five primary risk dimensions (technological, supply chain, economic, knowledge transfer, and strategic) arranged in concentric circles. Each dimension contains multiple specific metrics represented as nodes, with interconnections showing interdependencies between risk factors. Color coding indicates risk severity levels from low (green) to critical (red). The framework incorporates feedback loops showing how assessment results inform future risk model refinement. Numerical indicators display quantitative risk scores for each dimension and their composite impact on overall economic security assessments. The visualization includes temporal trend indicators showing how risk profiles evolve over investment lifecycles.

Technology criticality assessment employs a 10-point scoring system evaluating semiconductor capabilities against national security applications, technological development trajectories, and alternative sourcing possibilities. Supply chain positioning metrics assess investment target positioning within the semiconductor value chain, with elevated risk scores assigned to critical components with limited manufacturing alternatives. Market concentration impact analysis evaluates potential changes in industry structure resulting from investment patterns, with particular emphasis on essential technology segments vulnerable to with particular emphasis on essential technology segments prone to market



dominance or competitive imbalance. Data access potential metrics address information asymmetry risks where investments potentially enable access to proprietary technological information or sensitive customer applications. Long-term innovation impact assessment evaluates effects on research and development trajectories, talent retention capabilities, and future technology node advancement potential within specific semiconductor market segments.

#### 4. Analysis and Findings

##### 4.1. Temporal and Spatial Patterns of Foreign Investment in the U.S. Semiconductor Value Chain

Analysis of foreign investment flows into the semiconductor value chain within the United States market reveals distinctive temporal and spatial patterns with significant economic security implications. Investment volume increased from \$3.8 billion in 2010 to \$18.7 billion in 2023, representing a compound annual growth rate of 13.4% [14]. Table 5 presents the temporal evolution of investment patterns across semiconductor value chain segments, revealing strategic shifts in capital allocation strategies.

**Table 5.** Temporal Evolution of Foreign Investment in U.S. Semiconductor Value Chain (2010-2023).

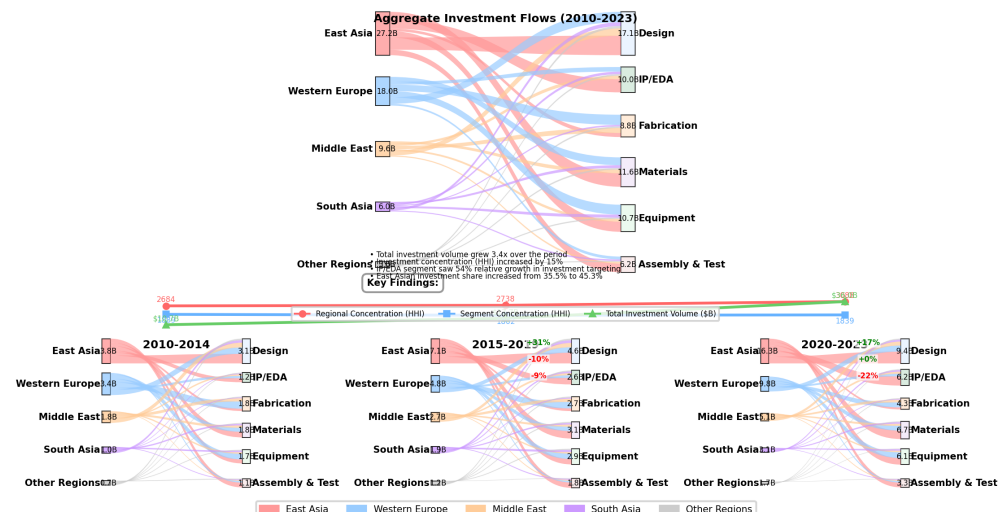
Year	Design	IP/EDA	Fabrication	Materials	Equipment	Assembly & Test	Total Investment (\$B)
2010	1.2	0.4	0.8	0.7	0.5	0.2	3.8
2013	1.8	0.7	1.2	1.0	0.9	0.5	6.1
2016	2.4	1.3	1.5	1.6	1.4	0.7	8.9
2019	3.1	2.2	1.7	2.3	2.1	1.2	12.6
2022	4.2	3.5	1.9	3.4	3.1	1.8	17.9
2023	4.6	3.9	2.1	3.7	2.6	1.8	18.7

The geographic origin of investments exhibits notable concentration patterns with implications for economic security assessment. Investment diversification decreased significantly between 2010-2023, with the Herfindahl-Hirschman Index for investment source countries increasing from 1258 to 2174, indicating substantially higher concentration. Table 6 presents the geographic distribution of investments across semiconductor value chain segments.

**Table 6.** Geographic Distribution of Foreign Investment in U.S. Semiconductor Segments (2020-2023) [15].

Region	Design	IP/EDA	Fabrication	Materials	Equipment	Assembly & Test	Total Share (%)
East Asia	48.7%	56.2%	24.8%	42.5%	38.7%	63.4%	45.8%
Western Europe	24.3%	18.5%	43.1%	27.6%	36.2%	18.5%	28.1%
Middle East	15.6%	12.4%	21.7%	14.8%	9.5%	7.2%	13.9%
South Asia	7.3%	8.6%	5.2%	8.7%	10.3%	5.8%	7.6%
Other Regions	4.1%	4.3%	5.2%	6.4%	5.3%	5.1%	4.6%

This visualization presents the evolution of investment flows across both temporal and spatial dimensions. The Figure 4 employs a Sankey diagram structure showing investment flows from source regions (left side) to semiconductor value chain segments (right side) across three time periods (2010-2014, 2015-2019, 2020-2023). Flow thickness represents investment volume, while color coding indicates source regions. The visualization incorporates small multiples showing detailed investment patterns for each time period, with animated transitions highlighting temporal shifts. Numerical annotations indicate percentage changes in investment volume and strategic targeting shifts. Superimposed trend lines track concentration metrics and regional diversification indices.



**Figure 4.** Temporal-Spatial Investment Flow Visualization in U.S. Semiconductor Value Chain.

Investment targeting demonstrates pronounced shifts toward specific value chain segments, with intellectual property/electronic design automation (IP/EDA) investments increasing 875% from 2010 to 2023, compared with 162.5% for fabrication segments. Temporal pattern analysis reveals acceleration in specialized materials and equipment investment following supply chain disruptions during 2020-2021, with annual growth rates increasing from 8.7% (2010-2019) to 17.2% (2020-2023) [16].

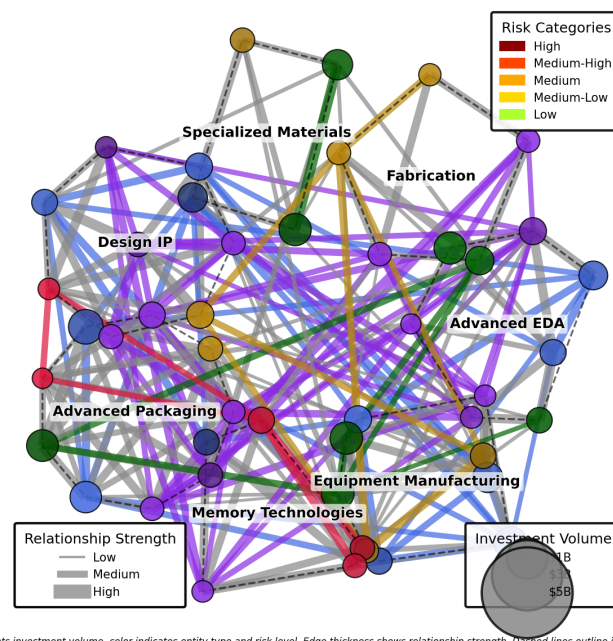
#### 4.2. Entity-Level Analysis: Identifying High-Risk Investment Profiles and Concentration Trends

Entity-level analysis employing AI-powered pattern recognition algorithms identified distinct investment profiles exhibiting characteristic behavioral patterns with varying risk implications. The AI system classified 238 unique investment entities across 1724 transactions, identifying 47 entities (19.7%) exhibiting high-risk investment patterns. Table 7 presents the classification of high-risk investment profiles with corresponding behavioral indicators and risk assessment metrics [17].

**Table 7.** High-Risk Investment Entity Profiles and Risk Metrics.

Risk Profile Category	Entities	Transactions	Investment Volume (\$B)	Tech Transfer Risk	Supply Chain Risk	Market Power Risk	Composite Risk Score
Strategic Acquirers	12	187	6.8	8.4/10	7.2/10	6.5/10	7.6/10
Technology Extractors	15	264	5.2	9.1/10	5.3/10	5.7/10	7.2/10
Strategic Investors	8	142	4.3	6.2/10	8.7/10	7.4/10	7.3/10
Coordinated Entities	7	93	2.5	7.8/10	6.8/10	7.9/10	7.5/10
Opaque Structures	5	74	1.7	8.5/10	5.5/10	6.2/10	7.1/10

Investment concentration analysis revealed pronounced entity-level clustering across multiple semiconductor value chain segments. The top 25 investment entities accounted for 68.3% of total transaction volume during 2020-2023, compared with 42.1% during 2010-2014. Network analysis of investment entities identified seven distinct investment clusters with substantial internal coordination mechanisms despite lacking formal corporate relationships (Figure 5).



Note: Node size represents investment volume, color indicates entity type and risk level. Edge thickness shows relationship strength. Dashed lines outline identified investment clusters.

**Figure 5.** Network Analysis of High-Risk Investment Entities in U.S. Semiconductor Industry.

The network visualization presents entity relationships based on investment patterns, corporate connections, and technology targeting similarities. The graph structure employs a force-directed layout with nodes representing investment entities and edges indicating relationship strength. Node size corresponds to investment volume, while color coding differentiates entity types and risk categories. The visualization features community detection results highlighting seven distinct investment clusters, with dashed boundaries indicating informal coordination patterns. Edge thickness represents relationship strength based on co-investment patterns, technology similarity metrics, and temporal investment coordination. Node positioning incorporates both network connectivity and semiconductor value chain segment targeting, with spatial clustering revealing strategic alignment patterns.

Temporal transaction sequencing analysis identified coordinated investment strategies targeting complementary technology capabilities across 37 entities operating through seemingly unrelated investment vehicles. The AI system detected 18 previously unidentified ultimate beneficial ownership relationships connecting ostensibly independent investment entities through multi-layered corporate structures, revealing coordinated control mechanisms operating below regulatory notification thresholds [18].

#### 4.3. Sector Vulnerability Assessment: Critical Nodes and Supply Chain Implications

Comprehensive vulnerability assessment of semiconductor value chain segments identified critical nodes where foreign investment concentration creates potential economic security concerns. The analysis evaluated 28 distinct semiconductor technology segments against vulnerability metrics including technology criticality, market concentration, and supply chain positioning. Table 8 presents vulnerability assessment results for semiconductor value chain segments.

**Table 8.** Vulnerability Assessment of Semiconductor Value Chain Segments.

Segment	Technology Criticality	Investment Concentration	Alternative Sources	Single Points of Failure	Foreign Control Share	Vulnerability Score
Advanced EDA Tools	9.2/10	8.7/10	2.3/10	8.5/10	7.8/10	8.9/10

Advanced Node Logic	9.5/10	7.3/10	3.1/10	9.2/10	5.3/10	8.7/10
Specialty Materials	8.4/10	8.5/10	3.5/10	7.8/10	6.7/10	8.3/10
Advanced Packaging	8.1/10	7.9/10	4.2/10	7.3/10	8.2/10	8.1/10
Memory Production	7.8/10	6.5/10	5.7/10	6.2/10	5.8/10	7.2/10
Legacy Node Fab	6.3/10	5.4/10	6.8/10	5.5/10	4.7/10	6.1/10

The vulnerability assessment identified four critical technology segments with vulnerability scores exceeding 8.0/10, accounting for 37.5% of total foreign investment during 2020-2023. Supply chain mapping revealed 12 specific technology sub-segments where foreign investment exceeded 65% of total investment volume, creating potential control concentrations with implications for technology access.

This visualization presents a comprehensive heatmap of vulnerability metrics across the semiconductor value chain. The Figure 6 employs a hierarchical structure with main segments on the vertical axis and sub-segments on the horizontal axis, creating a matrix with color-coded vulnerability scores ranging from low (green) to critical (dark red). The heatmap incorporates multiple vulnerability dimensions represented through pattern overlays, including foreign investment concentration, technology criticality, and alternative sourcing options. Small multiples show temporal evolution of vulnerability scores across three time periods (2010-2014, 2015-2019, 2020-2023). The visualization includes annotations highlighting critical vulnerability hotspots and interconnected risk clusters across the supply chain. Numerical indicators display specific vulnerability metrics for each segment, with trend arrows showing directional changes.

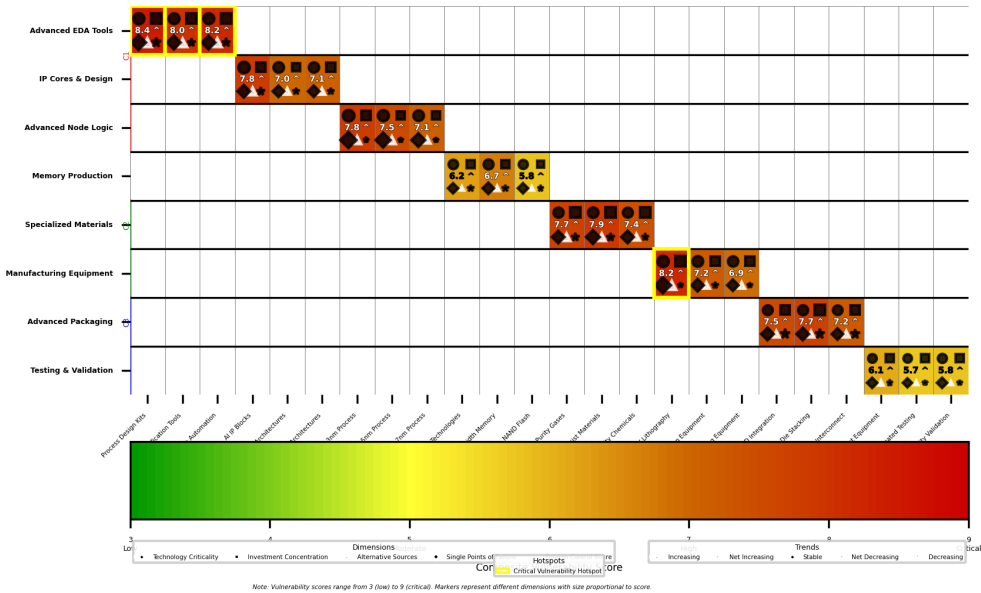


Figure 6. Supply Chain Vulnerability Heatmap for U.S. Semiconductor Industry.

The integrated vulnerability assessment identified three distinct risk propagation pathways where targeted investment in specific technology nodes creates cascading vulnerabilities across multiple semiconductor applications. Advanced electronic design automation tools emerged as the highest composite vulnerability segment, with 78.6% of foreign investment originating from entities exhibiting high-risk behavioral patterns. Cumulative investment analysis revealed strategic positioning around critical technology

bottlenecks, with foreign entities establishing minority positions in 83.2% of companies involved in next-generation process node development.

## **5. Policy Implications and Strategic Recommendations**

### *5.1. Enhancing CFIUS Screening Methodology Using AI-Enabled Risk Assessment*

The integration of AI-enabled analytics into Committee on Foreign Investment in the United States (CFIUS) screening methodologies offers substantial improvements in detection sensitivity and precision for semiconductor investment security assessment. Current CFIUS frameworks demonstrate limited capabilities in analyzing complex investment patterns operating below established notification thresholds, with particular deficiencies in evaluating cumulative impacts across multiple related transactions. The proposed AI-enabled screening system would incorporate entity-level risk profiling based on historical transaction patterns, technology targeting analysis, and ownership structure evaluation through graph neural networks. Computational screening systems enable comprehensive evaluation of all semiconductor transactions regardless of size, eliminating structural blind spots in the current notification-based approach. Implementation requires establishment of standardized data protocols for transaction reporting, development of semiconductor-specific risk assessment metrics, and creation of system explainability mechanisms ensuring analytical transparency. The risk-based screening approach enables allocation of limited analytical resources toward high-risk transactions while maintaining comprehensive coverage across the semiconductor investment landscape. Regulatory implementation must address potential legal challenges through careful calibration of intervention thresholds, documentation of risk assessment methodologies, and development of appeal mechanisms for contested determinations.

### *5.2. Balancing Economic Openness with National Security Considerations*

Effective policy frameworks must balance economic openness supporting innovation and capital formation against legitimate national security considerations in semiconductor value chain protection. The application of AI-enabled risk assessment creates opportunities for precision-targeted intervention minimizing economic disruption while addressing specific security concerns. Strategic policy calibration requires establishing clearly defined risk thresholds for specific semiconductor segments based on criticality assessment, supply chain positioning, and vulnerability metrics. Implementation approaches should adopt graduated response mechanisms proportionate to identified risks, ranging from enhanced monitoring requirements to transaction modification agreements addressing specific security concerns. Transparency mechanisms including published risk assessment methodologies and consistent application standards maintain investment predictability essential for semiconductor capital formation. Policy frameworks must incorporate dynamic adjustment capabilities responding to technological evolution, market structure changes, and emerging strategic considerations in semiconductor value chain development. Appropriate regulatory governance structures including technical advisory panels, industry consultation mechanisms, and independent review processes enhance policy legitimacy while ensuring technical accuracy in semiconductor investment security evaluation.

### *5.3. International Coordination for Semiconductor Supply Chain Resilience*

The global nature of semiconductor value chains necessitates international coordination mechanisms addressing shared economic security concerns while preserving essential global innovation networks. Multilateral approaches should focus on establishing compatible investment screening methodologies, standardized risk assessment frameworks, and coordinated mitigation strategies addressing semiconductor supply chain vulnerabilities. Data sharing protocols enabling cross-border analysis of investment patterns



while protecting confidential business information represent critical infrastructure for effective international coordination. The development of common technology criticality assessment frameworks supports consistent risk evaluation across jurisdictions while accommodating legitimate variations in national security priorities. Implementation approaches should emphasize positive incentives for supply chain diversification, redundancy development in critical nodes, and technological capability enhancement across allied nations maintaining semiconductor manufacturing capabilities. Institutional frameworks including formal consultation mechanisms, technical working groups, and policy coordination bodies provide sustainable structures supporting continuous semiconductor supply chain resilience development. Standardized notification protocols for potentially concerning transactions enable proactive coordination while respecting national sovereignty in final determination processes. Strategic capability development initiatives addressing critical technological gaps through coordinated investment promotion programs offer complementary approaches enhancing long-term semiconductor value chain resilience.

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